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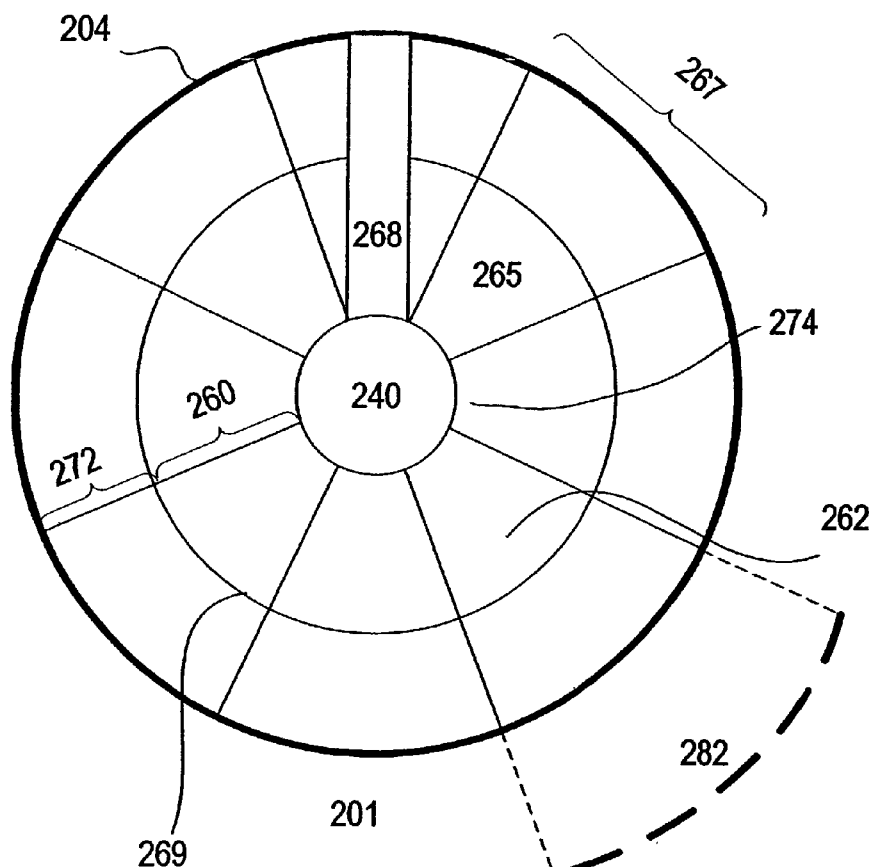
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(54) Title: LAYOUT AND DESIGN OF PRODUCTION FACILITY



(57) Abstract: An improved layout for a manufacturing facility is disclosed. The layout includes a production area which includes a hub which is at least partially surrounded by a production corridor. The production corridor comprises production stages used in the manufacturing process. The hub, having direct line-sight to the production stages, can easily monitor the manufacturing process.

WO 03/106785 A1